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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Complete if Known			
Application Number	10/565,623		
Filing Date	July 25, 2004		
First Named Inventor	Zeev ZALEVSKY		
Group Art Unit			
Examiner Name			
Attorney Docket Number	ZALEVSKY4		

	U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No.1	Document Number Number-Kind Code ^{2 (if known)}	Publication Date	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
	AA	US-5,571,641	11-05-1996	Bae		
	AB	US-5,235,463	08-10-1993	Broussoux et al.		
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	FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No.1	Foreign Patent Number Country Code ³ Number ⁴ Kind Code ⁵ (<i>if known</i>)	Publication Date MM-DD-YYYY	of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
	AC	EP-0 523 861 A2	01-20-1993	Mitsui Petrochemical		
	AD	EP-1 440 787 A2	07-28-2004	Canon Kabushiki Kaisha		
	AE	WO 01/37033 A2	05-25-2001	Corning Applied Tech.		
	AF	WO 03/005733 A1	01-16-2003	Explay Ltd.		
	AG	WO 2004/064410 A1	07-29-2004	Explay Ltd.		

Examiner	Date	· ·
Signature	Considered	

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Sheet

of 2

NON PATENT LITERATURE DOCUMENTS / OTHER INFORMATION					
Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²			
АН	LEE, H et al; "CMOS chip planarization by chemical mechanical polishing for a vertically stacked metal MEMS Integration"; Journal of Micromechanics and Microengineering; J.Micromech. Microeng 14 (2004), pp.108-115				
Al	BORRELLI, N.F; "Microoptics technology"; Marcel Dekker, Inc; 1999; pp. 18-38; New York				
AJ	JACKMAN, R.B. et al; "Design and Fabrication of Topologically Complex, Three-Dimensional Microstructures"; Academic Search Premier; 06/26/98, Vol. 280, Issue 5372				
AK	CALIXTO, S et al; "Ultraviolet self-generating relief micro-optical elements through crosslinking photopolymerization of liquid resins"; The European Physical Journal Applied Physics; XP-000948512; EDP Sciences; Vol.8, no.1; October 1999, pp. 29-35				
AL	GALE, M.T. et al; "Fabrication of continuous-relief micro-optical elements by direct laser writing in photoresists"; Optical Engineering; XP-000475099; Vol. 33, no. 11; pp. 3556-3566 11/01/94				
	AI AK	Include name of the author (in CAPITAL LETTERS), title of article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published AH LEE, H et al; "CMOS chip planarization by chemical mechanical polishing for a vertically stacked metal MEMS Integration"; Journal of Micromechanics and Microengineering; J.Micromech. Microeng 14 (2004), pp.108-115 AI BORRELLI, N.F; "Microoptics technology"; Marcel Dekker, Inc; 1999; pp. 18-38; New York AJ JACKMAN, R.B. et al; "Design and Fabrication of Topologically Complex, Three-Dimensional Microstructures"; Academic Search Premier; 06/26/98, Vol. 280, Issue 5372 AK CALIXTO, S et al; "Ultraviolet self-generating relief micro-optical elements through crosslinking photopolymerization of liquid resins"; The European Physical Journal Applied Physics; XP-000948512; EDP Sciences; Vol.8, no.1; October 1999, pp. 29-35 AL GALE, M.T. et al; "Fabrication of continuous-relief micro-optical elements by direct laser writing in photoresists";			

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¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.